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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 09/763,914
Applicant : STAHLER et al.
Filed : May 11, 2001
TC/A.U. : 1639
Examiner : Padmashri Ponnaluri

Docket No. : 2923-438
Customer No. : 06449
Confirmation No. : 3624

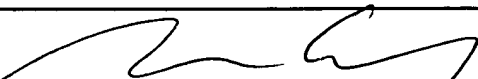
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

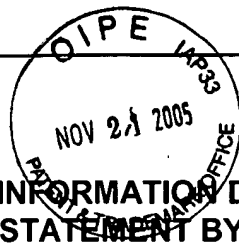
Director of the United States Patent
and Trademark Office
P.O. Box 1450
Alexandria, Virginia 22313-1450

Dear Sir:

Under the provisions of 37 C.F.R. §§ 1.56, 1.97 and 1.98,
Applicant submits herewith information that the Office may wish
to consider in examination of the subject application. Materials
submitted for consideration are listed on the attached form PTO-
1449.

Applicants believe that no fee is due for this submission,
however, if the Office deems a fee necessary, the Office is
authorized to charge our deposit account number 02-2135.

RESPECTFULLY SUBMITTED,					
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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

				<i>Complete if Known</i>	
				Application Number	09/763,914
				Filing Date	May 11, 2001
				First Named Inventor	STAHLER et al.
				Group Art Unit	1639
				Examiner Name	Padmashri Ponnaluri
				Confirmation No.	3624
Sheet	1	of	1	Attorney Docket Number	2923-438

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
	R	Berstch et al., "Study of the Spatial Resolution of a New 3D Microfabrication Process: the Microstereophotolithography Using a Dynamic Mask-Generator Technique," Journal of Photochemistry and Photobiology A: Chemistry, 107:275-281, 1997.	
	S	Davidson Mark, "A Microlens Direct-Write Concept for Lithography," SPIE, 3048:346-355.	
	T	Hoheisel, J.D., "Oligomer-Chip Technology," Trends in Biotechnology, 15(11):465-469, 1997.	
	U	Singh-Gasson et al., "Maskless Fabrication of Light-Directed Oligonucleotide Microarrays Using a Digital Micromirror Array," Nature Biotechnology, 17:974-978, 1999.	
	V	Retrieved from the Internet: "Digital Optical Chemistry System," http://innovation.swmed.edu/research/instrumentation/higher_pages	
Examiner Signature			Date Considered

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.
¹Unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.